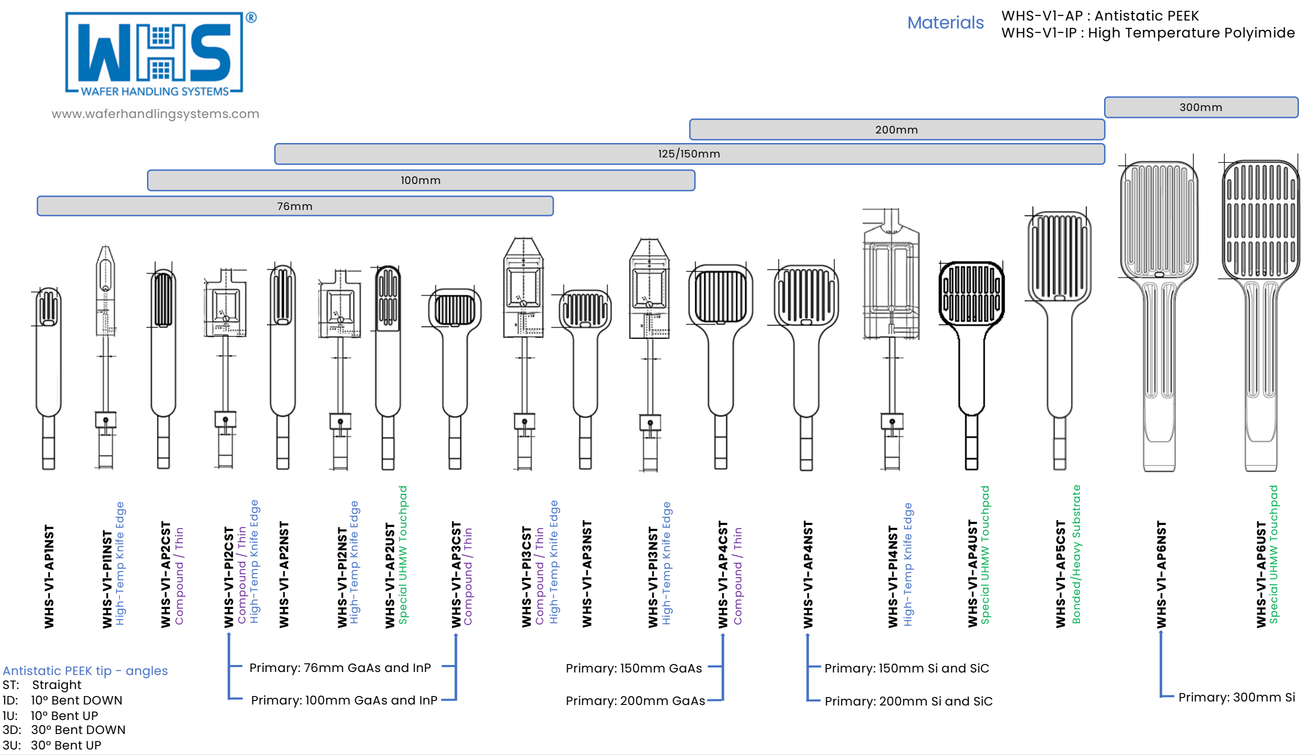
VACUUM WAND TIP SERIES

WHS offers 18 precision-engineered vacuum tips designed for diverse wafer handling applications in the semiconductor industry. WHS vacuum tips are manufactured, individually tested, and packaged in an advanced cleanroom environment, ensuring they are ready for use without the need for additional cleaning—unlike competitor models.

The primary tip material is ESD-safe PEEK Polyetheretherketone (AP), known for its chemical resistance, durability, and thermal stability up to 160°C. WHS provides 12 base models of PEEK vacuum tips, including options with thin-channel vacuum pockets, UHMW polyethylene touchpads for ultra-clean applications, and general-use tips. These tips accommodate wafers from 50 to 300 mm, with straight, 30°, or 10° bent configurations.

SELECTION OF ALL WHS TIPS



VACUUM WAND TIP SERIES

The 300 mm model (WHS-V1-AP6) features a 20° bend for ergonomic handling. For high-temperature applications, Polyimide (PI) vacuum tips are available. These machined tips feature knife-edge profiles, ideal for lifting wafers from flat surfaces. They are pre-mounted on stainless steel adapters with flash-annealed tubing, which can be bent to match application ergonomics without crimping. WHS offers six polyimide models, three of which are designed with thin-channel vacuum pockets for handling delicate compound or thin wafers.

All WHS-V1 vacuum tips are compatible with WHS vacuum wands and handles, as well as most competitor products. WHS also offers custom vacuum tips upon request, tailored to specific customer needs.

FEATURES AND ADVANTAGES

- 18 models for wafers from 50 mm to 300 mm
- ESD-safe PEEK, heat-resistant up to 160°C
- Polyimide tips for high-temp applications
- Cleanroom-tested and ready for use
- Straight or bent (10°, 20°, 30°) options

ITEM	SPECIFICATIONS
Sizes	50,76,100,125,150, 200, 300 mm
Material (AP)	PEEK - polyetheretherketone
Material (AP_U)	UHMW - polyethylene
Material (PI)	Polyimide
Cleanliness	ISO 3 (Class 1 FS209E)

REV022025

50-76 MM PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 50-76 mm wafers. Features 3° offset narrow-short 14 x 19 mm vacuum pocket. Available in standard vacuum pocket (AP1N). All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U) or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- SEMI standard wafer handling
- Antistatic PEEK material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	50-76 mm
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Length	104 mm
Vacuum pocket	14x19 mm (standard)

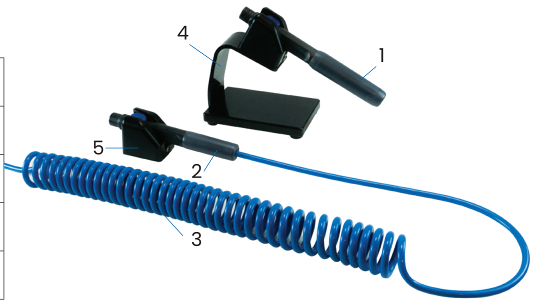
ORDERING INFORMATION

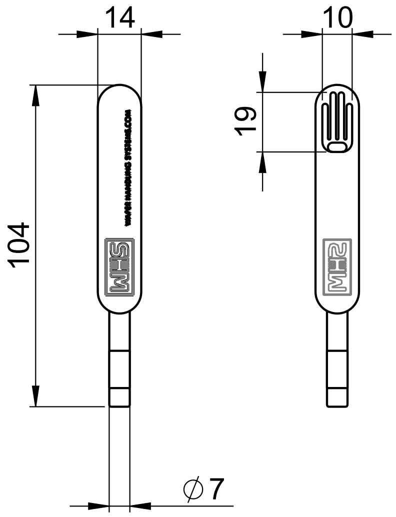
WHS-V1-	AP1NST

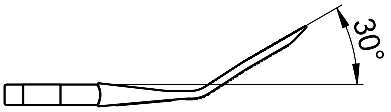
CODE	MODEL	
	AP1NST	Vacuum tip, PEEK, 50-76 mm, straight
	AP1N1D	Vacuum tip, PEEK, 50-76 mm, 10° down
	AP1N1U	Vacuum tip, PEEK, 50-76 mm, 10° up
	AP1N3D	Vacuum tip, PEEK, 50-76 mm, 30° down
	AP1N3U	Vacuum tip, PEEK, 50-76 mm, 30° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5



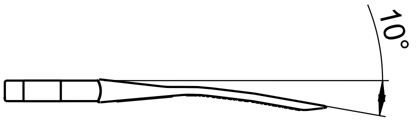




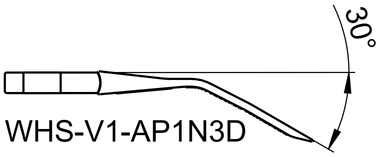
WHS-V1-AP1N3U
Vacuum Tip, PEEK, 50-76mm, 30°Up

WHS-V1-AP1N1U
Vacuum Tip, PEEK, 50-76mm, 10°Up

WHS-V1-AP1NST
Vacuum Tip, PEEK, 50-76mm, Straight



WHS-V1-AP1N1D
Vacuum Tip, PEEK, 50-76mm, 10°Down



WHS-V1-AP1N3D
Vacuum Tip, PEEK, 50-76mm, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP1NST

Vacuum Tip, PEEK, 50-76mm, Straight

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REV022025

76-150 MM PEEK COMPOUND/THIN VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 76-150 mm wafers. Features 3° offset narrow-long 14x31 mm vacuum pocket. Available in standard vacuum pocket (AP2N) ; thin wafer /compound wafer vacuum pocket (AP2C); and standard with special polyethylene touchpad (AP2U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- Thin and compound wafer handling
- Antistatic PEEK material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	76-150 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	14x31 mm (thin-compound)

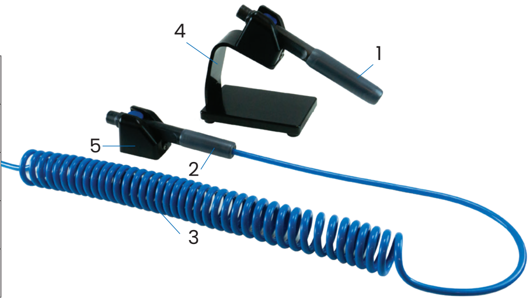
ORDERING INFORMATION

WHS-V1-	AP2CST

CODE	MODEL	
	AP2CST	Vacuum tip, PEEK, 76-150 mm, compound/thin, straight
	AP2C1D	Vacuum tip, PEEK, 76-150 mm, compound/thin, 10° down
	AP2C1U	Vacuum tip, PEEK, 76-150 mm, compound/thin, 10° up
	AP2C3D	Vacuum tip, PEEK, 76-150 mm, compound/thin, 30° down
	AP2C3U	Vacuum tip, PEEK, 76-150 mm, compound/thin, 30° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5



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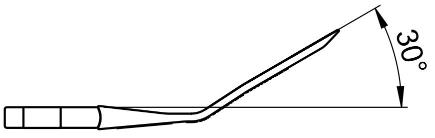
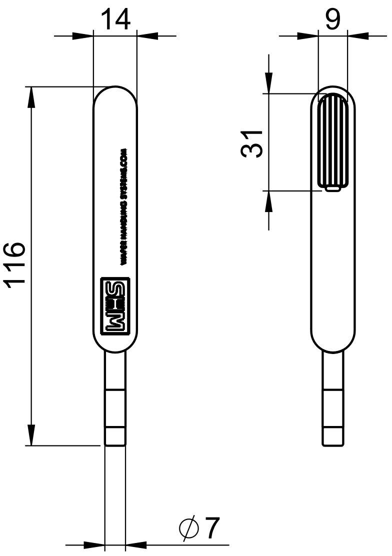


WHS-V1-AP2C3U

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, 30°Up

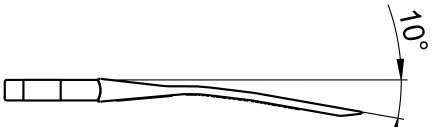


WHS-V1-AP2C1U

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, 10°Up

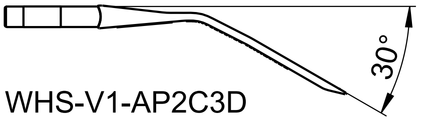
WHS-V1-AP2CST

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, Straight



WHS-V1-AP2C1D

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, 10°Down



WHS-V1-AP2C3D

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP2CST

Vacuum Tip, PEEK, 50-100mm, Compound/Thin, Straight

REV022025

76-150 MM PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 76-150 mm wafers. Features 3° offset narrow-long 14 x 31 mm vacuum pocket. Available in standard Vacuum pocket (AP2N) ; thin wafer /compound wafer Vacuum pocket (AP2C); and standard with special polyethylene touchpad (AP2U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- SEMI Standard Wafer handling
- Antistatic PEEK Material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	76-150 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	14x31 mm (standard)

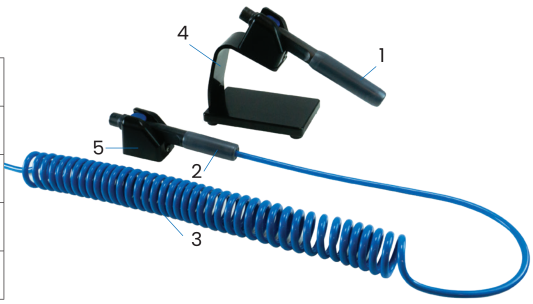
ORDERING INFORMATION

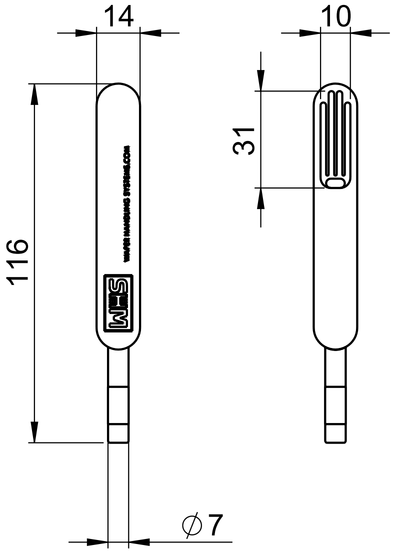
WHS-V1- AP2NST

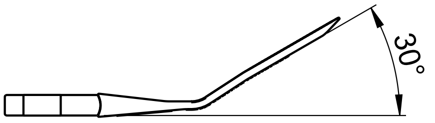
CODE	MODEL	
	AP2NST	Vacuum tip, PEEK, 76-150 mm, straight
	AP2N1D	Vacuum tip, PEEK, 76-150 mm, 10° down
	AP2N1U	Vacuum tip, PEEK, 76-150 mm, 10° up
	AP2N3D	Vacuum tip, PEEK, 76-150 mm, 30° down
	AP2N3U	Vacuum tip, PEEK, 76-150 mm, 30° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5



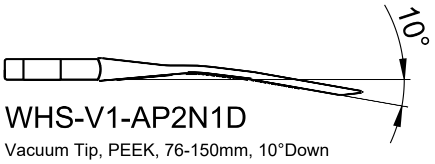




WHS-V1-AP2N3U
Vacuum Tip, PEEK, 76-150mm, 30°Up

WHS-V1-AP2N1U
Vacuum Tip, PEEK, 76-150mm, 10°Up

WHS-V1-AP2NST
Vacuum Tip, PEEK, 76-150mm, Straight



WHS-V1-AP2N1D
Vacuum Tip, PEEK, 76-150mm, 10°Down

WHS-V1-AP2N3D
Vacuum Tip, PEEK, 76-150mm, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP2NST

Vacuum Tip, PEEK, 76-150mm, Straight

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REV022025

76-150 MM UHMW/PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 76-150 mm wafers. Features 3° offset narrow-long 14 x 31 mm Vacuum pocket. Available in standard Vacuum pocket (AP2N) ; thin wafer /compound wafer Vacuum pocket (AP2C); and standard with special polyethylene touchpad (AP2U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

ITEM	SPECIFICATIONS
Type	Press-fit
Size	76-150 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	14x31 mm (standard)
Touchpad pocket	UHMW PE

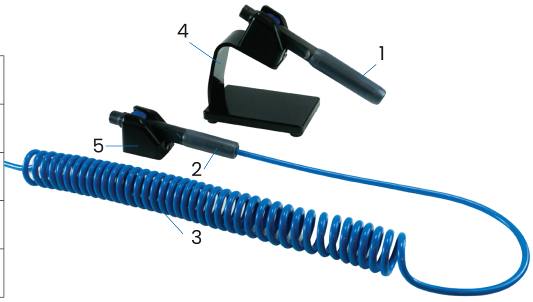
ORDERING INFORMATION

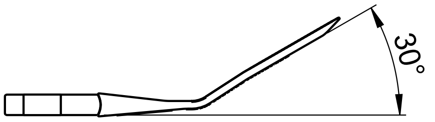
WHS-V1- AP2UST

CODE	MODEL
AP2UST	Vacuum tip, UHMW/PEEK, 76-150 mm, straight
AP2U1D	Vacuum tip, UHMW/PEEK, 76-150 mm, 10° down
AP2U1U	Vacuum tip, UHMW/PEEK, 76-150 mm, 10° up
AP2U3D	Vacuum tip, UHMW/PEEK, 76-150 mm, 30° down
AP2U3U	Vacuum tip, UHMW/PEEK, 76-150 mm, 30° up

RELATED PRODUCTS

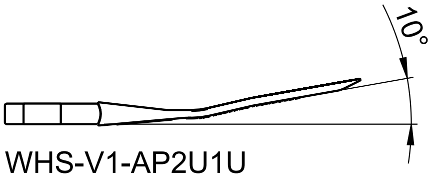
WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





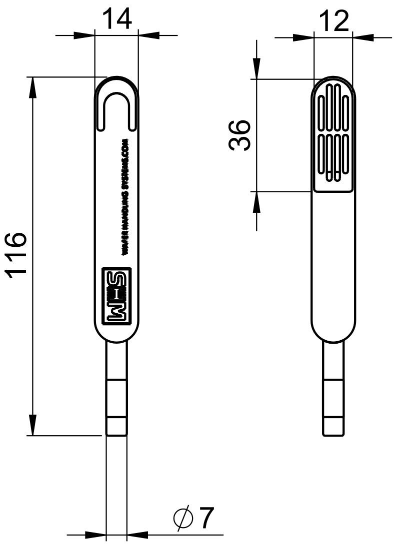
WHS-V1-AP2U3U

Vacuum Tip, UHMW/PEEK,76-100mm, 30°Up



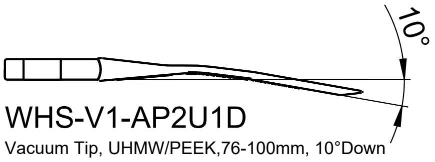
WHS-V1-AP2U1U

Vacuum Tip, UHMW/PEEK,76-100mm, 10°Up



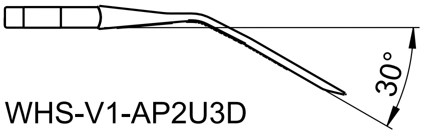
WHS-V1-AP2UST

Vacuum Tip, UHMW/PEEK,76-100mm, Straight



WHS-V1-AP2U1D

Vacuum Tip, UHMW/PEEK,76-100mm, 10°Down



WHS-V1-AP2U3D

Vacuum Tip, UHMW/PEEK,76-100mm, 30°Down

Material:
Body: Antistatic PEEK
Foil: Polyethylene Film

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WHS-V1-AP2UST

Vacuum Tip, UHMW/PEEK, 76-100mm, Straight

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76-150 MM PEEK COMPOUND/THIN VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 76-150 mm wafers. Features 3° offset wide-short 30 x 19 mm vacuum pocket. Available in standard vacuum pocket (AP3N) and thin wafer /compound wafer vacuum pocket (AP3C). All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- Thin and compound wafer handling
- Antistatic PEEK material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	76-150 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	30x19 mm (thin-compound)

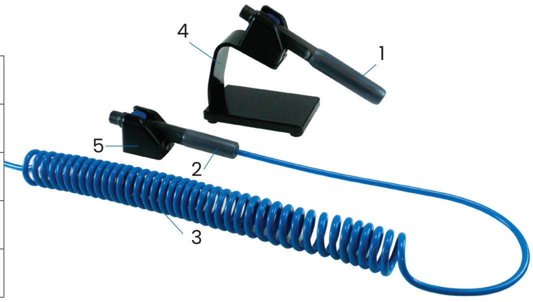
ORDERING INFORMATION

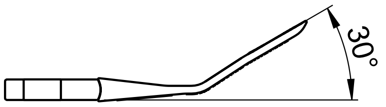
WHS-V1- AP3CST

CODE	MODEL	
	AP3CST	Vacuum tip, PEEK, 76-150 mm, compound/thin, straight
	AP3C1D	Vacuum tip, PEEK, 76-150 mm, compound/thin, 10° down
	AP3C1U	Vacuum tip, PEEK, 76-150 mm, compound/thin, 10° up
	AP3C3D	Vacuum tip, PEEK, 76-150 mm, compound/thin, 30° down
	AP3C3U	Vacuum tip, PEEK, 76-150 mm, compound/thin, 30° up

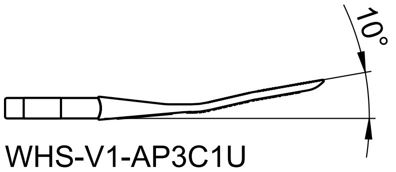
RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5

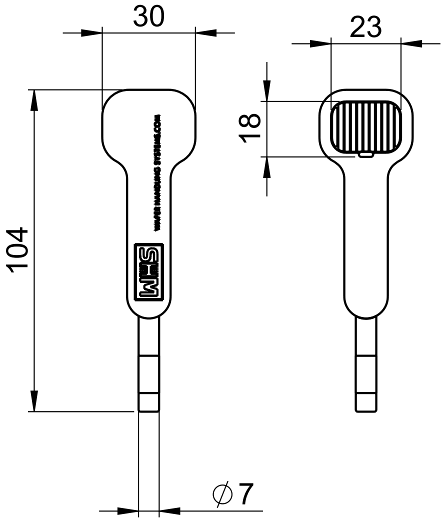




WHS-V1-AP3C3U
Vacuum Tip, PEEK, 76-150mm, Compound/Thin, 30°Up



WHS-V1-AP3C1U
Vacuum Tip, PEEK, 76-150mm, Compound/Thin, 10°Up



WHS-V1-AP3CST
Vacuum Tip, PEEK, 76-150mm Compound/Thin

WHS-V1-AP3C1D
Vacuum Tip, PEEK, 76-150mm, Compound/Thin, 10°Down

WHS-V1-AP3C3D
Vacuum Tip, PEEK, 76-150mm, Compound/Thin, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP3CST

Vacuum Tip, PEEK, 76-150mm Compound/Thin

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

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76-150 MM PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 76-150 mm wafers. Features 3° offset wide-short 30 x 19 mm Vacuum pocket. Available in standard Vacuum pocket (AP3N) and thin wafer /compound wafer Vacuum pocket (AP3C). All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- SEMI standard wafer handling
- Antistatic PEEK material

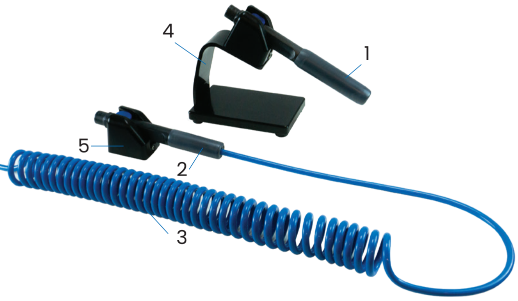
ITEM	SPECIFICATIONS
Type	Press-fit
Size	76-150 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	30x19 mm (standard)

ORDERING INFORMATION

WHS-V1-	AP3NST	
CODE	**MODEL**	
	AP3NST	Vacuum tip, PEEK, 76-150 mm, straight
	AP3N1D	Vacuum tip, PEEK, 76-150 mm, 10° down
	AP3N1U	Vacuum tip, PEEK, 76-150 mm, 10° up
	AP3N3D	Vacuum tip, PEEK, 76-150 mm, 30° down
	AP3N3U	Vacuum tip, PEEK, 76-150 mm, 30° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5



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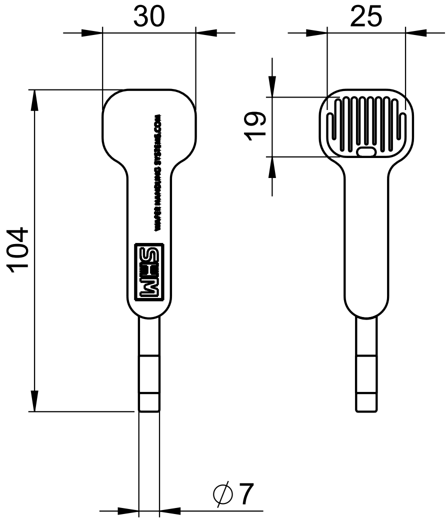
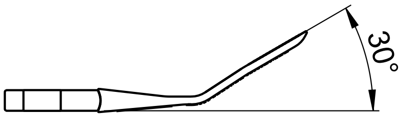
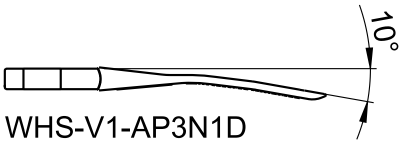




WHS-V1-AP3N3U
Vacuum Tip, PEEK, 76-150mm, 30°Up

WHS-V1-AP3N1U
Vacuum Tip, PEEK, 76-150mm, 10°Up

WHS-V1-AP3NST
Vacuum Tip, PEEK, 76-150mm, Straight



WHS-V1-AP3N1D
Vacuum Tip, PEEK, 76-150mm, 10°Down

WHS-V1-AP3N3D
Vacuum Tip, PEEK, 76-150mm, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP3NST

Vacuum Tip, PEEK, 76-150mm, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

100-200 MM PEEK INSERTION PREVENTION BUMP VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 100-200 mm wafers. Features 3° offset wide-wide 36 x 36 mm vacuum pocket. Available in standard vacuum pocket (AP4N); standard pocket with backside insertion prevention bump (AP4B); thin wafer /compound wafer Vacuum pocket (AP4C); and standard with special polyethylene touchpad (AP4U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- SEMI standard wafer handling
- Insertion prevention bump

ITEM	SPECIFICATIONS
Type	Press-fit
Size	100-200 mm wafer handling
Material	Antistatic PEEK
Bent	Straight
Vacuum pocket	36x36 mm
	Insertion prevention with standard vacuum pocket

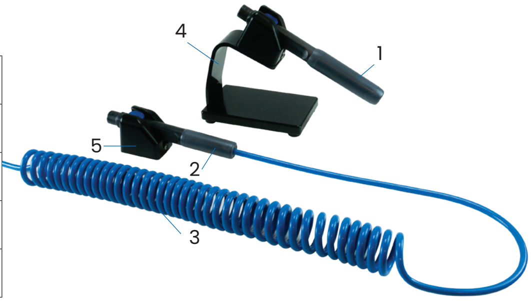
ORDERING INFORMATION

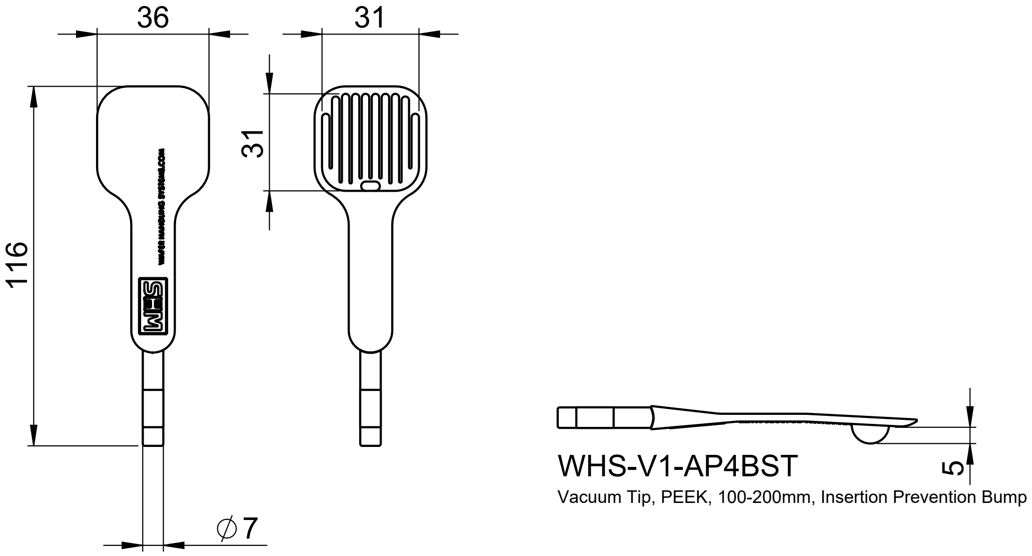
WHS-V1- AP4BST

CODE	MODEL	
	AP4BST	Vacuum tip, PEEK, 100-200 mm, insertion prevention bump

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





Material:
Antistatic PEEK

WHS-V1-AP4BST

Vacuum Tip, PEEK, 100-200mm, Insertion Prevention Bump

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

100-200 MM PEEK COMPOUND/THIN VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 100-200 mm wafers. Features 3° offset wide-wide 36 x 36 mm vacuum pocket. Available in standard vacuum pocket (AP4N); standard pocket with backside insertion prevention bump (AP4B); thin wafer /compound wafer vacuum pocket (AP4C); and standard with special polyethylene touchpad (AP4U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

ITEM	SPECIFICATIONS
Type	Press-fit
Size	100-200 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	36x36 mm (thin-compound)

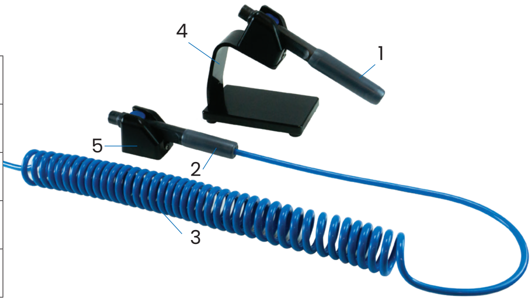
ORDERING INFORMATION

WHS-V1- AP4CST

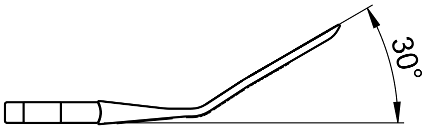
CODE	MODEL
AP4CST	Vacuum tip, PEEK, 100-200 mm, compound/thin, straight
AP4C1D	Vacuum tip, PEEK, 100-200 mm, compound/thin, 10° down
AP4C1U	Vacuum tip, PEEK, 100-200 mm, compound/thin, 10° up
AP4C3D	Vacuum tip, PEEK, 100-200 mm, compound/thin, 30° down
AP4C3U	Vacuum tip, PEEK, 100-200 mm, compound/thin, 30° up

RELATED PRODUCTS

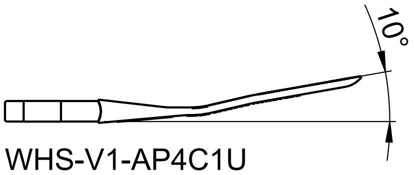
WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5



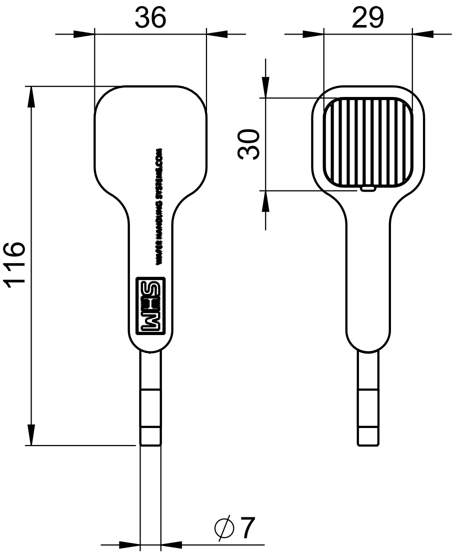
REV022025



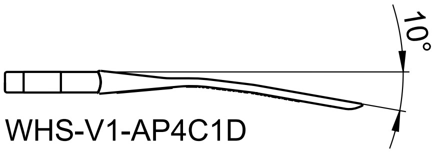
WHS-V1-AP4C3D
Vacuum Tip, PEEK, 150-200mm, Compound/Thin, 30°Up



WHS-V1-AP4C1U
Vacuum Tip, PEEK, 150-200mm, Compound/Thin, 10°Up



WHS-V1-AP4CST
Vacuum Tip, PEEK, 150-200mm, Compound/Thin, Straight



WHS-V1-AP4C1D
Vacuum Tip, PEEK, 150-200mm, Compound/Thin, 10°Down

WHS-V1-AP4C3D
Vacuum Tip, PEEK, 150-200mm, Compound/Thin, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP4CST

Vacuum Tip, PEEK, 150-200mm, Compound/Thin, Straight

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REV022025

100-200 MM PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 100-200 mm wafers. Features 3° offset wide-wide 36 x 36 mm vacuum pocket. Available in standard vacuum pocket (AP4N); standard pocket with backside insertion prevention bump (AP4B); thin wafer /compound wafer vacuum pocket (AP4C); and standard with special polyethylene touchpad (AP4U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

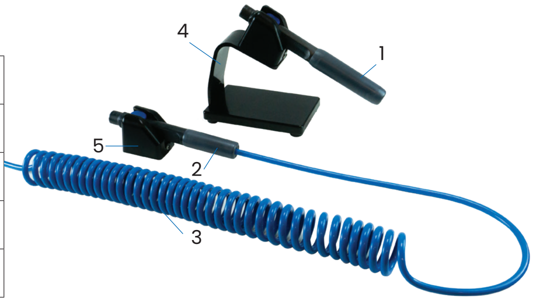
ITEM	SPECIFICATIONS
Type	Press-fit
Size	100-200 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	36x36 mm (Standard)

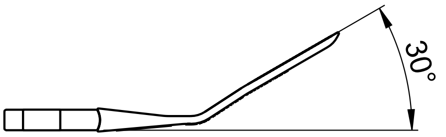
ORDERING INFORMATION

WHS-V1-	AP4NST	
CODE	**MODEL**	
	AP4NST	Vacuum tip, PEEK, 100-200 mm, straight
	AP4N1D	Vacuum tip, PEEK, 100-200 mm, 10° down
	AP4N1U	Vacuum tip, PEEK, 100-200 mm, 10° up
	AP4N3D	Vacuum tip, PEEK, 100-200 mm, 30° down
	AP4N3U	Vacuum tip, PEEK, 100-200 mm, 30° up

RELATED PRODUCTS

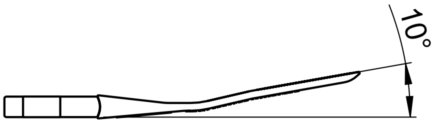
WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





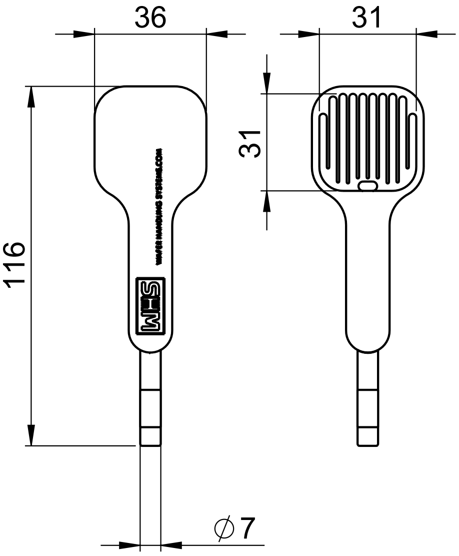
WHS-V1-AP4N3U

Vacuum Tip, PEEK, 100-200mm, 30°Up



WHS-V1-AP4N1U

Vacuum Tip, PEEK, 100-200mm, 10°Up

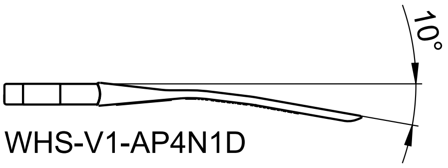


WHS-V1-AP4NST

Vacuum Tip, PEEK, 100-200mm, Straight

WHS-V1-AP4BST

Vacuum Tip, PEEK, 100-200mm, Insertion Prevention Bump



WHS-V1-AP4N1D

Vacuum Tip, PEEK, 100-200mm, 10°Down

WHS-V1-AP4N3D

Vacuum Tip, PEEK, 100-200mm, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP4NST

Vacuum Tip, PEEK, 100-200mm, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

100-200 MM UHMW/PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 100-200 mm wafers. Features 3º offset wide-wide 36 x 36 mm Vacuum pocket. Available in standard vacuum pocket (AP4N); standard pocket with backside insertion prevention bump (AP4B); thin wafer /compound wafer Vacuum pocket (AP4C); and standard with special polyethylene touchpad (AP4U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10º up (1U), bent 10º down (1D), bent 30º up (3U), or bent 30º down (3D) based on each wafer handling application. ISO 3 compatible.

ITEM	SPECIFICATIONS
Type	Press-fit
Size	100-200 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10º down bent, 10º up bent, 30º down bent or 30º up bent
Length	116 mm
Vacuum pocket	36x36 mm (standard)
Touchpad pocket	UHMW PE

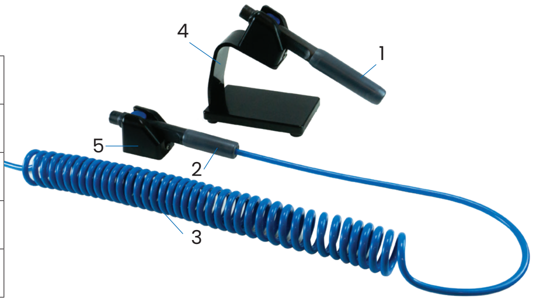
ORDERING INFORMATION

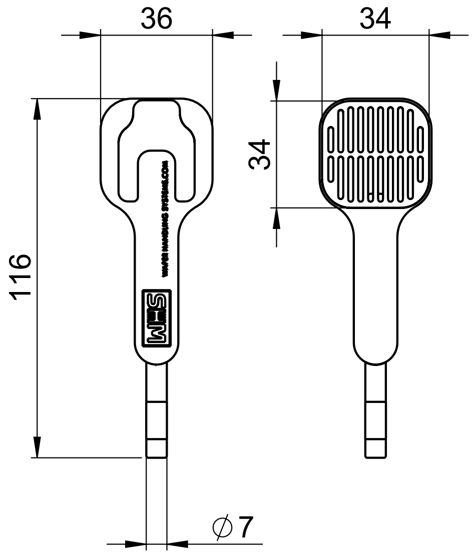
WHS-V1- AP4UST

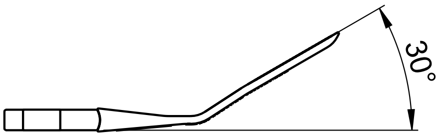
CODE	MODEL	
	AP4UST	Vacuum tip, UHMW/PEEK, 100-200 mm, straight
	AP4U1D	Vacuum tip, UHMW/PEEK, 100-200 mm, 10º down
	AP4U1U	Vacuum tip, UHMW/PEEK, 100-200 mm, 10º up
	AP4U3D	Vacuum tip, UHMW/PEEK, 100-200 mm, 30º down
	AP4U3U	Vacuum tip, UHMW/PEEK, 100-200 mm, 30º up

RELATED PRODUCTS

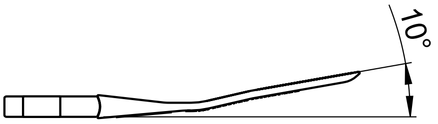
WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





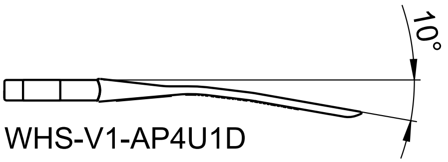


WHS-V1-AP4U3U
Vacuum Tip, UHMW/PEEK,150-200mm, 30°Up



WHS-V1-AP4U1U
Vacuum Tip, UHMW/PEEK,150-200mm, 10°Up

WHS-V1-AP4UST
Vacuum Tip, UHMW/PEEK, 150-200mm, Straight



WHS-V1-AP4U1D
Vacuum Tip, UHMW/PEEK, 150-200mm, 10°Down

WHS-V1-AP4U3D
Vacuum Tip, UHMW/PEEK,150-200mm, 30°Down

Material:
Body: Antistatic PEEK
Foil: Polyethylene Film

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WHS-V1-AP4UST

Vacuum Tip, UHMW/PEEK, 150-200mm, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

100-200 MM PEEK BONDED/HEAVY VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 100-200 mm heavy-weight wafers. Features 3° offset wide-extra long 36 x 50 mm vacuum pocket. Available in standard vacuum pocket design (AP4N). Available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 30° up (3U), or bent 30° down (3D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- Heavy and bonded wafer handling
- Antistatic PEEK material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	100-200 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 30° down bent or 30° up bent
Vacuum pocket	36x50 mm
	Heavy-bonded

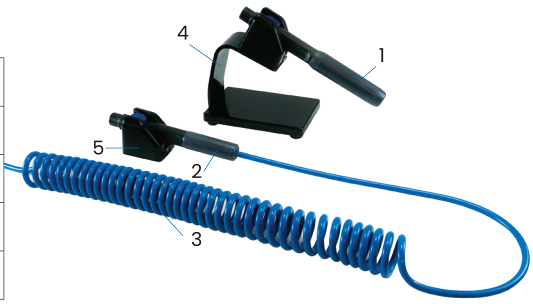
ORDERING INFORMATION

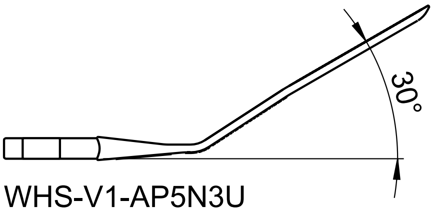
WHS-V1- AP5NST

CODE	MODEL	
	AP5NST	Vacuum tip, PEEK, Bonded/heavy, straight
	AP5N1D	Vacuum tip, PEEK, Bonded/heavy, 10° down
	AP5N1U	Vacuum tip, PEEK, Bonded/heavy, 10° up
	AP5N3D	Vacuum tip, PEEK, Bonded/heavy, 30° down
	AP5N3U	Vacuum tip, PEEK, Bonded/heavy, 30° up

RELATED PRODUCTS

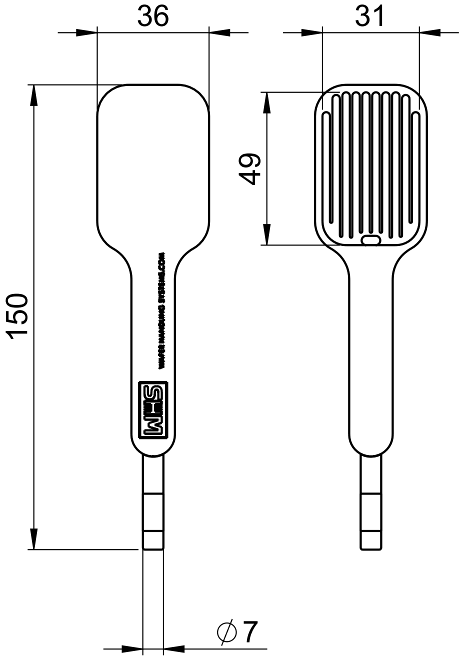
WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5

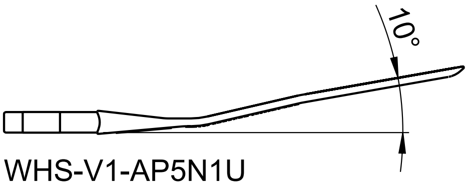




WHS-V1-AP5N3U

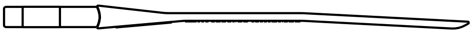
Vacuum Tip, PEEK, Bonded/Heavy, 30°Up





WHS-V1-AP5N1U

Vacuum Tip, PEEK, Bonded/Heavy, 10°Up

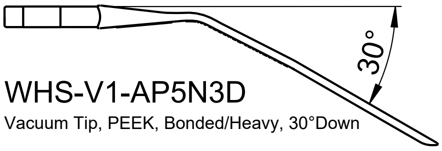


WHS-V1-AP5NST

Vacuum Tip, PEEK, Bonded/Heavy, Straight

WHS-V1-AP5N1D

Vacuum Tip, PEEK, Bonded/Heavy, 10°Down



WHS-V1-AP5N3D

Vacuum Tip, PEEK, Bonded/Heavy, 30°Down

Material:
Antistatic PEEK

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WHS-V1-AP5NST

Vacuum Tip, PEEK, Bonded/Heavy, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

300 MM PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 300 mm wafers. Features 3° offset 50 x 76 mm vacuum pocket. Available in standard vacuum pocket design (AP6N) and standard with special polyethylene touchpad (AP6U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 20° up (2U), or bent 20° down (2D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- SEMI standard wafer handling
- Antistatic PEEK material

ITEM	SPECIFICATIONS
Type	Press-fit
Size	300 mm wafer handling
Material	Antistatic PEEK
Bent	Straight, 10° down bent, 10° up bent, 20° down bent or 20° up bent
Vacuum pocket	50x75 mm (standard)

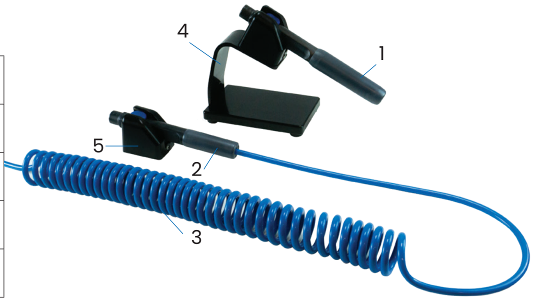
ORDERING INFORMATION

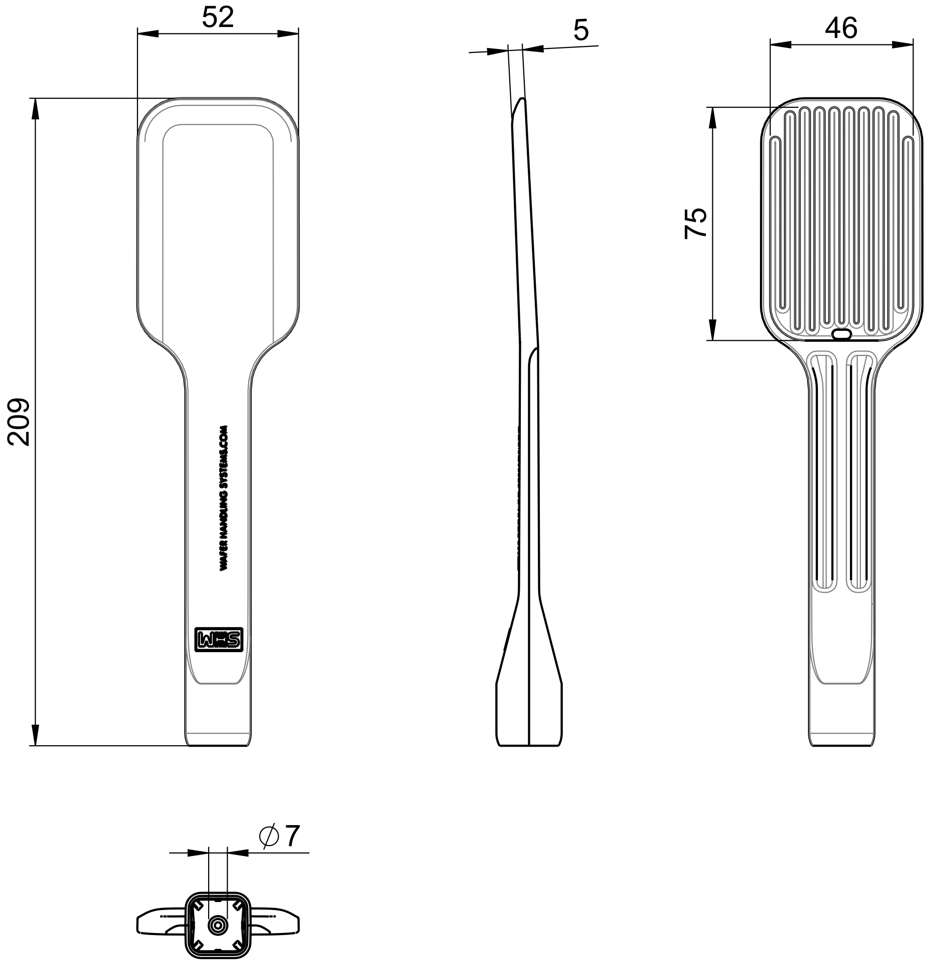
WHS-V1-	AP6NST

CODE	MODEL	
	AP6NST	Vacuum tip, PEEK, 300 mm, straight
	AP6N1D	Vacuum tip, PEEK, 300 mm, 10° down
	AP6N1U	Vacuum tip, PEEK, 300 mm, 10° up
	AP6N2D	Vacuum tip, PEEK, 300 mm, 20° down
	AP6N2U	Vacuum tip, PEEK, 300 mm, 20° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





Material:
Antistatic PEEK

WAFER HANDLING SYSTEMS.COM

WHS-V1-AP6NST

Vacuum Tip, PEEK, 300mm, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

300 MM UHMW/PEEK VACUUM TIP

Antistatic conductive PEEK vacuum wand tip for handling of 300 mm wafers. Features 3° offset 50 x 76 mm vacuum pocket. Available in standard vacuum pocket design (AP6N) and standard with special polyethylene touchpad (AP6U) for handling virgin, EPI, optical wafers, and front side contact applications. All versions are available straight (ST), bent 10° up (1U), bent 10° down (1D), bent 20° up (2U), or bent 20° down (2D) based on each wafer handling application. ISO 3 compatible.

FEATURES AND ADVANTAGES

- Non-marking UHMW on antistatic PEEK

ITEM	SPECIFICATIONS
Type	Press-fit
Size	300 mm wafer handling
Material	Antistatic PEEK/UHMW
Bent	Straight, 10° down bent, 10° up bent, 20° down bent or 20° up bent
Vacuum pocket	50x75 mm (standard)
Touchpad pocket	UHMW PE

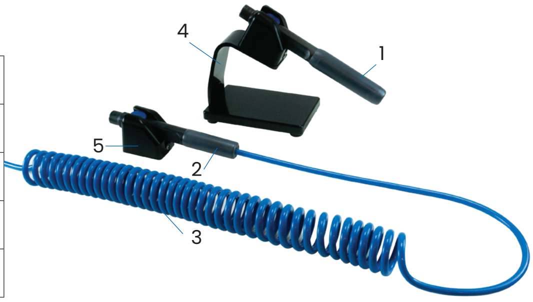
ORDERING INFORMATION

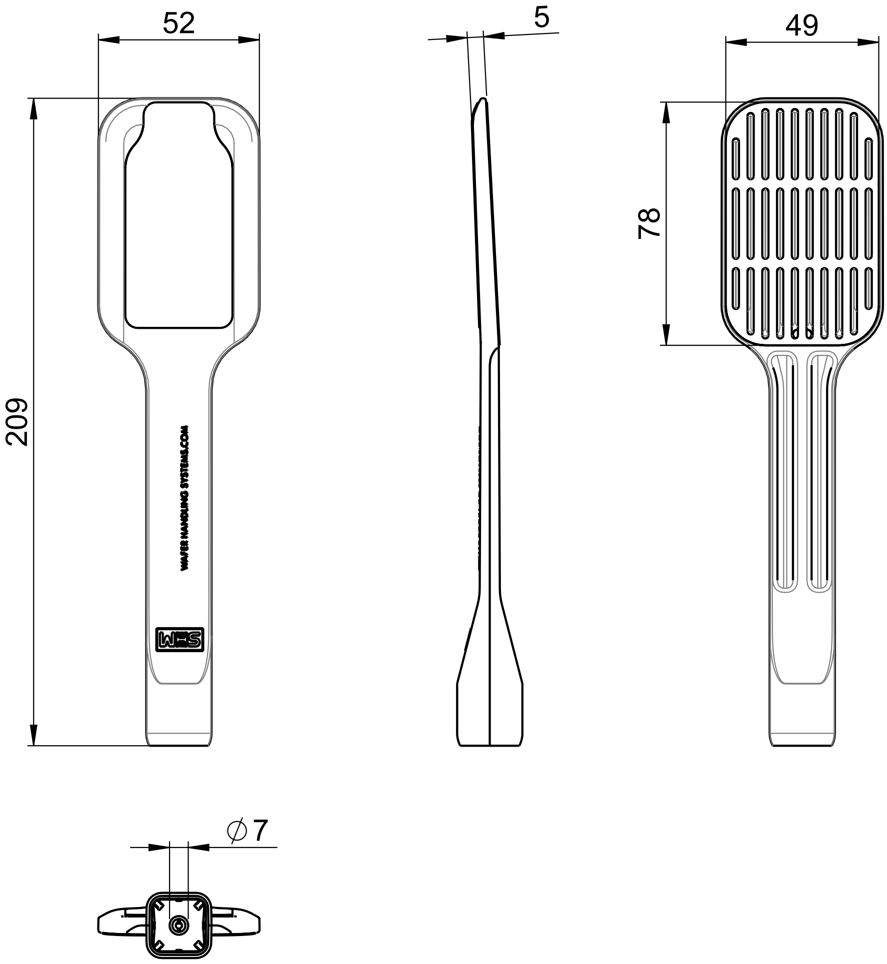
WHS-V1- AP6UST

CODE	MODEL	
	AP6UST	Vacuum tip, UHMW/PEEK, 300 mm, straight
	AP6U1D	Vacuum tip, UHMW/PEEK, 300 mm, 10° down
	AP6U1U	Vacuum tip, UHMW/PEEK, 300 mm, 10° up
	AP6U2D	Vacuum tip, UHMW/PEEK, 300 mm, 20° down
	AP6U2U	Vacuum tip, UHMW/PEEK, 300 mm, 20° up

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5





Material:
Body: Antistatic PEEK
Foil: Polyethylene Film

WAFER HANDLING SYSTEMS.COM

WHS-V1-AP6UST

Vacuum Tip, UHMW/PEEK, 300mm, Straight

date: 01-10-2022 | scale: 1:2 | entity: mm | This drawing is owned by WHS trademark and may not be copied, reproduced or shown to third parties without written permission.

REV022025

VACUUM TIP - POLYIMIDE 50-76 MM KNIFE-EDGE

High-temperature polyimide vacuum wand tip for special handling of substrates to/from a platen, evaporator, hotplate or flat surface in a cleanroom environment. Features sharp edged profile with low depth vacuum pocket designed for safely handling compound wafers. Press-fit type installation, includes tip, tubing and adapter - fully assembled. For handling of 50-76 mm wafer substrates and is ISO 3.

FEATURES AND ADVANTAGES

- Knife-edge spatula - platen unloading
- High-temperature polyimide
- Tip assembly - tip, tubing, adapter

ITEM	SPECIFICATIONS
Type	Vacuum tip assembly
Size	50-76 mm wafer handling
Material	High temperture polyimide
Bent	Spatula knife-edge for platens/ hotplates

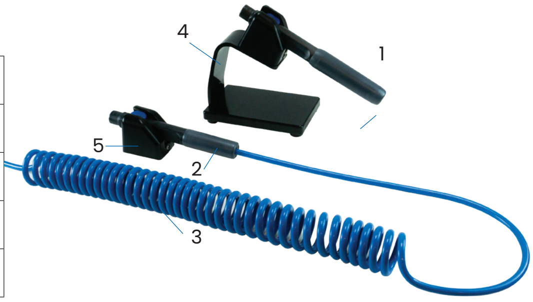
ORDERING INFORMATION

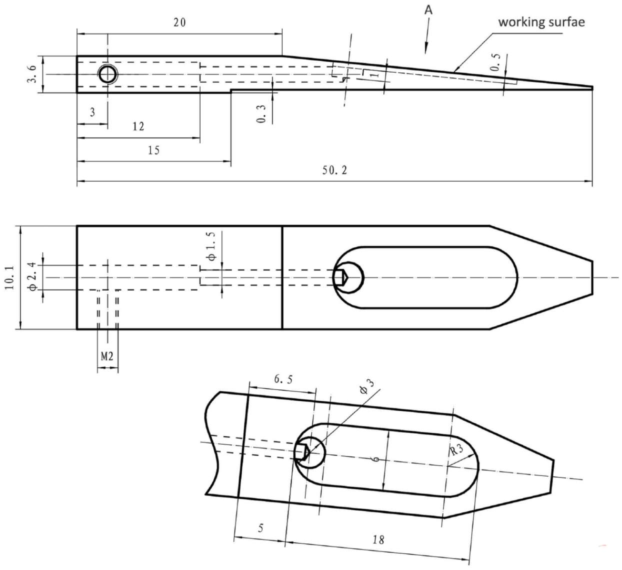
WHS-V1- PI1NST

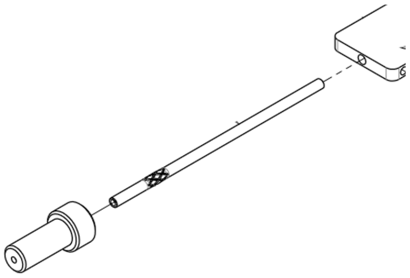
CODE	MODEL	
	PI1NST	Vacuum tip, polyimide , 50-76 mm, knife-edge

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5







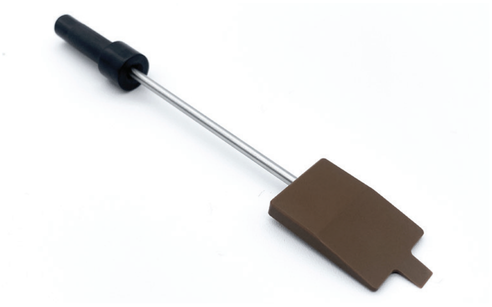
Material:
Polyimide

WHS-V1-PI1NST

Vacuum Tip, Polyimide, 50-76,, Straight

50-100 MM POLYIMIDE VACUUM TIP

High-temperature polyimide vacuum wand tip for special handling of substrates to/from a platen, evaporator, hotplate or flat surface in a cleanroom environment. Features sharp edged profile with shallow vacuum pocket or Vacuum pocket designed for safely handling compound wafers or silicon and glass wafers. Press-fit type installation, includes tip, tubing and adapter - fully assembled. For handling of 50-100 mm wafer substrates and is ISO 3.



FEATURES AND ADVANTAGES

- Knife-edge spatula - platen unloading
- High-temperature polyimide
- Tip assembly - tip, tubing, adapter

ITEM	SPECIFICATIONS
Type	Vacuum tip assembly
Size	50-100 mm wafer handling
Material	High temperture polyimide
Bent	Spatula knife-edge for platens/ hotplates

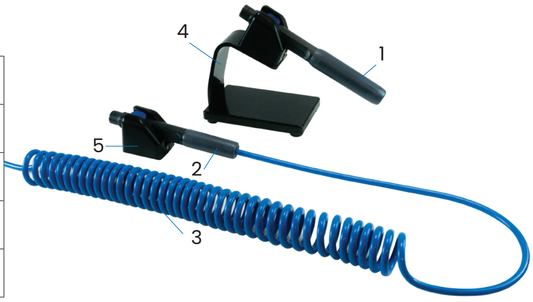
ORDERING INFORMATION

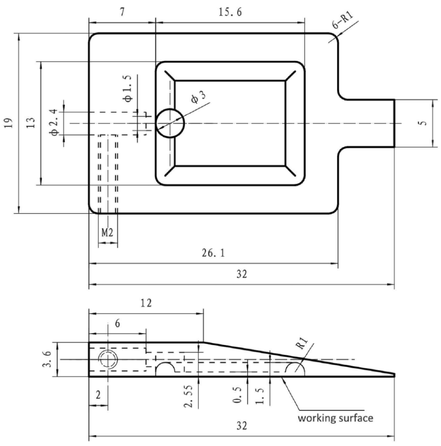
WHS-V1-	PI2CST

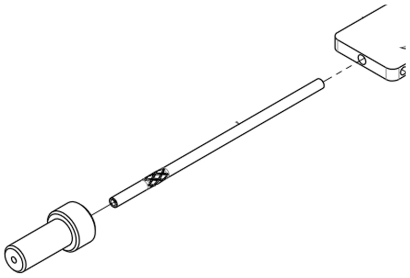
CODE	MODEL	
	PI2CST	Vacuum tip, polyimide , 50-100 mm compound, knife edge (for compound wafers)
	PI2NST	Vacuum tip, polyimide , 50-100 mm, knife edge (for silicon and glass wafers)

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5







Material:
Polyimide

WHS-V1-PI2CST

Vacuum Tip, Polyimide, 50-100mm,, Straight, Compound/Thin

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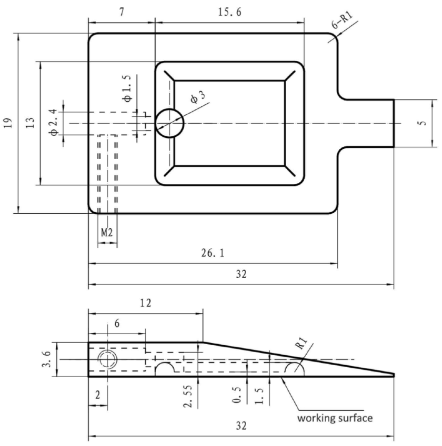
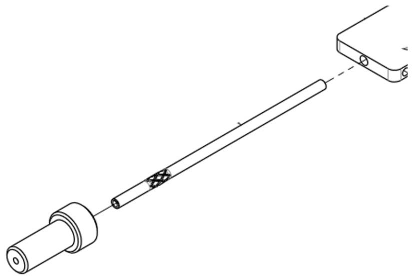




Material:
Polyimide

WAFER HANDLING SYSTEMS.COM

WHS-V1-PI2NST

Vacuum Tip, Polyimide, 50-100mm,, Straight

REV022025

150 MM POLYIMIDE 150 MM VACUUM TIP

High-temperature polyimide vacuum wand tip for special handling of substrates to/from a platen, evaporator, hotplate or flat surface in a cleanroom environment. Features sharp edged profile with shallow vacuum pocket or vacuum pocket designed for safely handling compound wafers or silicon and glass wafers. Press-fit type installation, includes tip, tubing and adapter - fully assembled. For handling of 150 mm wafer substrates and is ISO 3.

FEATURES AND ADVANTAGES

- Knife-Edge Spatula - Platen Unloading
- High-Temperature Polyimide
- Tip Assembly - Tip, Tubing, Adapter

ITEM	SPECIFICATIONS
Type	Vacuum tip assembly
Size	150 mm wafer handling
Material	High temperture polyimide
Bent	Spatula knife-edge for platens/ hotplates

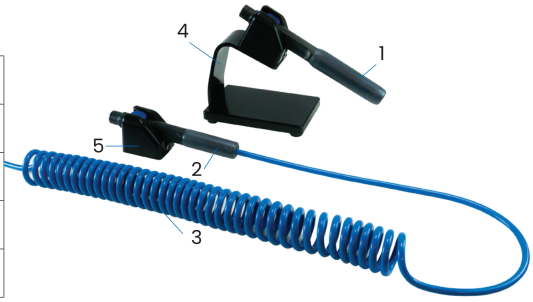
ORDERING INFORMATION

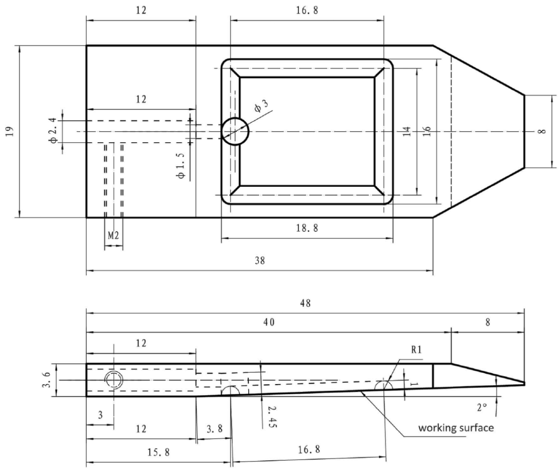
WHS-V1-	PI3CST

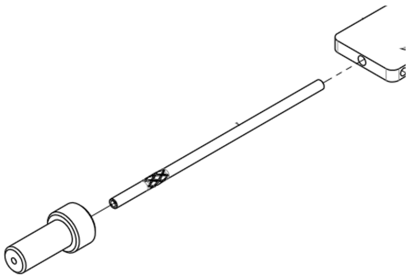
CODE	MODEL	
	PI3CST	Vacuum tip, polyimide , 150 mm compound, knife edge (for compound wafers)
	PI3NST	Vacuum tip, polyimide , 150 mm, knife edge (for silicon and glass wafers)

RELATED PRODUCTS

WHS-V2-LG	Vacuum wand handle large grip	1
WHS-V2-SM	Vacuum wand handle small grip	2
WHS-V3-CC	Coil cord, conductive polyurethane	3
WHS-V4-TT	Vacuum wand holder, tabletop	4
WHS-V4-WM	Vacuum wand holder, wall mount	5







Material:
Polyimide

WHS-V1-PI3CST

Vacuum Tip, Polyimide, 150mm,, Straight, Compound/Thin

WAFER HANDLING SYSTEMS.COM

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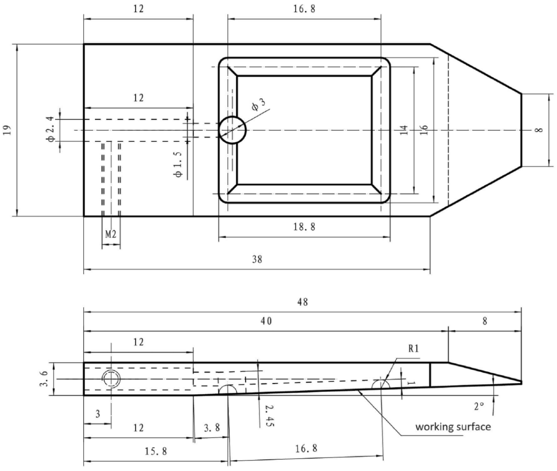

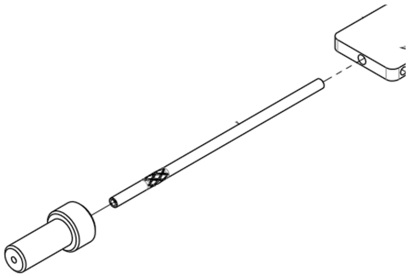

Material:
Polyimide

WAFER HANDLING SYSTEMS.COM

WHS-V1-PI3NST

Vacuum Tip, Polyimide, 150mm,, Straight

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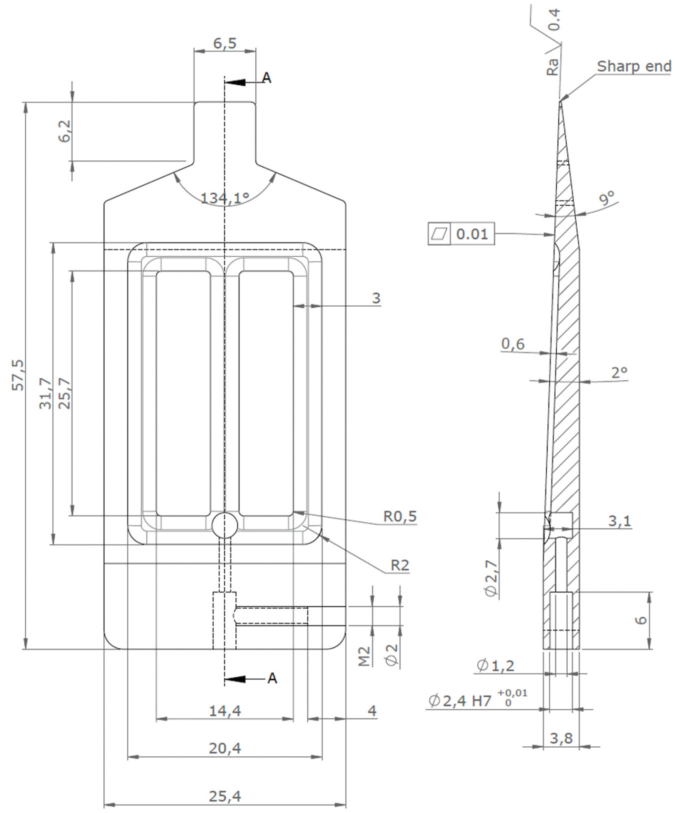

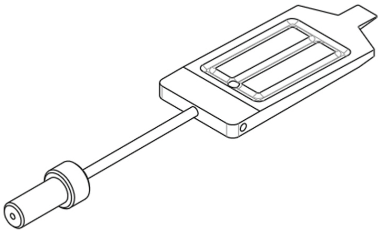

Material:
Polyimide

WAFER HANDLING SYSTEMS.COM

WHS-V1-PI4NST

Vacuum Tip, Polyimide, 200mm,, Straight